

# Nikolay Chkhalo

## List of Publications by Citations

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160  
papers

1,109  
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18  
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g-index

166  
ext. papers

1,316  
ext. citations

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avg, IF

4.37  
L-index

#	Paper	IF	Citations
160	Roughness measurement and ion-beam polishing of super-smooth optical surfaces of fused quartz and optical ceramics. <i>Optics Express</i> , <b>2014</b> , 22, 20094-106	3.3	48
159	Next generation nanolithography based on Ru/Be and Rh/Sr multilayer optics. <i>AIP Advances</i> , <b>2013</b> , 3, 082130	1.5	44
158	Advanced materials for multilayer mirrors for extreme ultraviolet solar astronomy. <i>Applied Optics</i> , <b>2016</b> , 55, 2126-35	0.2	41
157	Ion-beam polishing of fused silica substrates for imaging soft x-ray and extreme ultraviolet optics. <i>Applied Optics</i> , <b>2016</b> , 55, 1249-56	0.2	39
156	High performance La/B4C multilayer mirrors with barrier layers for the next generation lithography. <i>Applied Physics Letters</i> , <b>2013</b> , 102, 011602	3.4	38
155	A source of a reference spherical wave based on a single mode optical fiber with a narrowed exit aperture. <i>Review of Scientific Instruments</i> , <b>2008</b> , 79, 033107	1.7	34
154	Extended model for the reconstruction of periodic multilayers from extreme ultraviolet and X-ray reflectivity data. <i>Journal of Applied Crystallography</i> , <b>2017</b> , 50, 1428-1440	3.8	31
153	Laboratory methods for investigations of multilayer mirrors in extreme ultraviolet and soft x-ray region <b>2004</b> ,		31
152	Problems in the application of a null lens for precise measurements of aspheric mirrors. <i>Applied Optics</i> , <b>2016</b> , 55, 619-25	0.2	29
151	Multilayer X-ray mirrors based on La/B4C and La/B9C. <i>Technical Physics</i> , <b>2010</b> , 55, 1168-1174	0.5	26
150	Note: A stand on the basis of atomic force microscope to study substrates for imaging optics. <i>Review of Scientific Instruments</i> , <b>2015</b> , 86, 016102	1.7	25
149	Resolving capacity of the circular Zernike polynomials. <i>Optics Express</i> , <b>2015</b> , 23, 14677-94	3.3	22
148	Particulars of studying the roughness of substrates for multilayer X-ray optics using small-angle X-ray reflectometry, atomic-force, and interference microscopy. <i>Bulletin of the Russian Academy of Sciences: Physics</i> , <b>2011</b> , 75, 67-72	0.4	22
147	Free-standing spectral purity filters for extreme ultraviolet lithography. <i>Journal of Micro/Nanolithography, MEMS, and MOEMS</i> , <b>2012</b> , 11, 021115-1	0.7	22
146	Properties of laser-sputtered Ti/Be multilayers. <i>Review of Scientific Instruments</i> , <b>1992</b> , 63, 1478-1481	1.7	22
145	Current status and development prospects for multilayer X-ray optics at the Institute for Physics of Microstructures, Russian Academy of Sciences. <i>Journal of Surface Investigation</i> , <b>2017</b> , 11, 1-19	0.5	21
144	Thin film multilayer filters for solar EUV telescopes. <i>Applied Optics</i> , <b>2016</b> , 55, 4683-90	0.2	19

143	Short-period multilayer X-ray mirrors. <i>Journal of Synchrotron Radiation</i> , <b>2003</b> , 10, 358-60	2.4	19
142	Influence of barrier interlayers on the performance of Mo/Be multilayer mirrors for next-generation EUV lithography. <i>Optics Express</i> , <b>2018</b> , 26, 33718-33731	3.3	18
141	The evolution of roughness of supersmooth surfaces by ion-beam etching. <i>Bulletin of the Russian Academy of Sciences: Physics</i> , <b>2012</b> , 76, 163-167	0.4	17
140	Laboratory reflectometer for the investigation of optical elements in a wavelength range of 5–50 nm: description and testing results. <i>Quantum Electronics</i> , <b>2017</b> , 47, 385-392	1.8	16
139	Observation of extreme ultraviolet light emission from an expanding plasma jet with multiply charged argon or xenon ions. <i>Applied Physics Letters</i> , <b>2018</b> , 113, 153502	3.4	15
138	Application of point diffraction interferometry for middle spatial frequency roughness detection. <i>Optics Letters</i> , <b>2015</b> , 40, 159-62	3	14
137	A stand for a projection EUV nanolithographer-multiplier with a design resolution of 30 nm. <i>Bulletin of the Russian Academy of Sciences: Physics</i> , <b>2011</b> , 75, 49-52	0.4	14
136	Angle resolved photoelectron spectroscopy as applied to X-ray mirrors: an in depth study of Mo/Si multilayer systems. <i>Physical Chemistry Chemical Physics</i> , <b>2019</b> , 21, 25002-25010	3.6	14
135	Conversion efficiency of a laser-plasma source based on a Xe jet in the vicinity of a wavelength of 11 nm. <i>AIP Advances</i> , <b>2018</b> , 8, 105003	1.5	14
134	Study of oxidation processes in Mo/Be multilayers. <i>AIP Advances</i> , <b>2018</b> , 8, 075202	1.5	12
133	Testing and correction of optical elements with subnanometer precision. <i>Nanotechnologies in Russia</i> , <b>2008</b> , 3, 602-610	0.6	12
132	Composite Yb:YAG/sapphire thin-disk active elements for high-energy high-average power lasers. <i>Optics Letters</i> , <b>2020</b> , 45, 387	3	12
131	Device for the precise shape correction of optical surfaces by ion-beam and reactive plasma etching. <i>Journal of Surface Investigation</i> , <b>2013</b> , 7, 913-915	0.5	11
130	Source for extreme ultraviolet lithography based on plasma sustained by millimeter-wave gyrotron radiation. <i>Journal of Micro/Nanolithography, MEMS, and MOEMS</i> , <b>2012</b> , 11, 021123-1	0.7	11
129	Extreme-ultraviolet source based on the electron-cyclotron-resonance discharge. <i>JETP Letters</i> , <b>2008</b> , 88, 95-98	1.2	11
128	Reflective Schmidt-Cassegrain system for large-aperture telescopes. <i>Applied Optics</i> , <b>2016</b> , 55, 4430-5	0.2	11
127	A double-stream Xe:He jet plasma emission in the vicinity of 6.7 nm. <i>Applied Physics Letters</i> , <b>2018</b> , 112, 221101	3.4	11
126	Deposition of Mo/Si multilayers onto MEMS micromirrors and its utilization for extreme ultraviolet maskless lithography. <i>Journal of Vacuum Science and Technology B: Nanotechnology and Microelectronics</i> , <b>2017</b> , 35, 062002	1.3	10

125	Evolution of the roughness of amorphous quartz surfaces and Cr/Sc multilayer structures upon exposure to ion-beam etching. <i>Bulletin of the Russian Academy of Sciences: Physics</i> , <b>2011</b> , 75, 61-63	0.4	10
124	Physical limitations of measurement accuracy of the diffraction reference wave interferometers. <i>Bulletin of the Russian Academy of Sciences: Physics</i> , <b>2010</b> , 74, 53-56	0.4	10
123	Shortwave projection nanolithography. <i>Herald of the Russian Academy of Sciences</i> , <b>2008</b> , 78, 279-285	0.7	10
122	Atomic-hydrogen cleaning of Sn from Mo/Si and DLC/Si extreme ultraviolet multilayer mirrors. <i>Journal of Micro/ Nanolithography, MEMS, and MOEMS</i> , <b>2012</b> , 11, 021118-1	0.7	9
121	Determining angles of incidence and heights of quantum dot faces by analyzing X-ray diffuse and specular scattering. <i>Technical Physics</i> , <b>2009</b> , 54, 561-568	0.5	9
120	Preparation and roughness metrology of supersmooth optical surfaces. <i>Journal of Surface Investigation</i> , <b>2015</b> , 9, 761-764	0.5	8
119	Precision aspherization of the surface of optical elements by ion-beam etching. <i>Journal of Surface Investigation</i> , <b>2015</b> , 9, 765-770	0.5	8
118	Use of cluster secondary ions for minimization of matrix effects in the SIMS depth profiling of La/B4C multilayer nanostructures. <i>Journal of Surface Investigation</i> , <b>2010</b> , 4, 807-810	0.5	8
117	Investigation of supersmooth optical surfaces and multilayer elements using soft X-ray radiation. <i>Technical Physics</i> , <b>2013</b> , 58, 1371-1379	0.5	7
116	Problem of roughness detection for supersmooth surfaces <b>2011</b> ,		7
115	Multilayer thin-film filters of extreme ultraviolet and soft X-ray spectral regions. <i>Bulletin of the Russian Academy of Sciences: Physics</i> , <b>2010</b> , 74, 46-49	0.4	7
114	Analysis of cross-correlation of interface roughness in multilayer structures with ultrashort periods. <i>Journal of Experimental and Theoretical Physics</i> , <b>2006</b> , 103, 346-353	1	7
113	Quantum Confinement Effect in a Nanoscale Mo/Si Multilayer Structure. <i>Journal of Physical Chemistry C</i> , <b>2020</b> , 124, 17795-17805	3.8	7
112	The diffraction efficiency of echelle gratings increased by ion-beam polishing of groove surfaces. <i>Technical Physics Letters</i> , <b>2016</b> , 42, 844-847	0.7	7
111	Diffraction limited X-ray optics: technology, metrology, applications. <i>Physics-Uspekhi</i> , <b>2020</b> , 63, 67-82	2.8	6
110	Chemically amplified resists for high-resolution lithography. <i>Russian Microelectronics</i> , <b>2013</b> , 42, 165-175	0.5	6
109	Polished siall substrates for X-ray optics. <i>Journal of Surface Investigation</i> , <b>2013</b> , 7, 612-616	0.5	6
108	Application of cluster beams for the physics and technologies of microstructures. <i>Journal of Surface Investigation</i> , <b>2017</b> , 11, 496-500	0.5	6

107	Raman scattering study of nanoscale Mo/Si and Mo/Be periodic multilayer structures. <i>Journal of Vacuum Science and Technology A: Vacuum, Surfaces and Films</i> , <b>2020</b> , 38, 063408	2.9	6
106	Sub-micrometer resolution proximity X-ray microscope with digital image registration. <i>Review of Scientific Instruments</i> , <b>2015</b> , 86, 063701	1.7	5
105	An extreme ultraviolet radiation source based on plasma heated by millimeter range radiation. <i>Bulletin of the Russian Academy of Sciences: Physics</i> , <b>2011</b> , 75, 64-66	0.4	5
104	Two-mirror projection objective of a nanolithographer at $\lambda = 13.5$ nm. <i>Bulletin of the Russian Academy of Sciences: Physics</i> , <b>2011</b> , 75, 57-60	0.4	5
103	Detecting quasi-periodic $\{11n\}$ ( $n = 7\text{--}11$ ) faces in samples with Ge/Si quantum dots by grazing X-ray reflectometry. <i>Technical Physics Letters</i> , <b>2010</b> , 36, 108-111	0.7	5
102	A plane wave diffraction on a pin-hole in a film with a finite thickness and real electrodynamic properties <b>2008</b> ,		5
101	Matrix based algorithm for ion-beam figuring of optical elements. <i>Precision Engineering</i> , <b>2021</b> , 69, 29-35	2.9	5
100	Maskless X-Ray Lithography Based on Microoptical Electromechanical Systems and Microfocus X-Ray Tubes. <i>Journal of Surface Investigation</i> , <b>2018</b> , 12, 944-952	0.5	5
99	Absolutely Calibrated Spectrally Resolved Measurements of Xe Laser Plasma Radiation Intensity in the EUV Range. <i>Technical Physics</i> , <b>2018</b> , 63, 1507-1510	0.5	5
98	Microfocus X-Ray Tubes with a Silicon Autoemission Nanocathode as an X-Ray Source. <i>Bulletin of the Lebedev Physics Institute</i> , <b>2018</b> , 45, 1-5	0.5	5
97	Mo/Si Multilayer Mirrors with B <sub>4</sub> C and Be Barrier Layers. <i>Journal of Surface Investigation</i> , <b>2019</b> , 13, 169-173	1.7	4
96	Set of Multilayer X-Ray Mirrors for a Double-Mirror Monochromator Operating in the Wavelength Range of 0.41–5.5 nm. <i>Journal of Surface Investigation</i> , <b>2019</b> , 13, 1-7	0.5	4
95	Sputtering of carbon using hydrogen ion beams with energies of 60–800 eV. <i>Nuclear Instruments &amp; Methods in Physics Research B</i> , <b>2016</b> , 387, 73-76	1.2	4
94	Polishing the surface of a z-cut KDP crystal by neutralized argon ions. <i>Applied Optics</i> , <b>2018</b> , 57, 6911-6915	1.7	4
93	On the problems of the application of atomic-force microscopes for studying the surface roughness of elements for imaging optics. <i>Journal of Surface Investigation</i> , <b>2013</b> , 7, 797-801	0.5	4
92	Design of a soft X-ray and extreme UV reflectometer equipped with a high-resolution monochromator and high-brightness laser-plasma radiation source. <i>Journal of Surface Investigation</i> , <b>2015</b> , 9, 726-734	0.5	4
91	Manufacturing and characterization of diffraction quality normal incidence optics for the XEUV range <b>2011</b> ,		4
90	Thermal loads of X-ray tubes with a fixed anode under long-duration exposure. <i>High Temperature</i> , <b>2006</b> , 44, 766-772	0.8	4

89	Matched characterization of super-multiperiod superlattices. <i>Journal Physics D: Applied Physics</i> , <b>2020</b> , 53, 455103	3	4
88	Matched X-Ray Reflectometry and Diffractometry of Super-Multiperiod Heterostructures Grown by Molecular Beam Epitaxy. <i>Semiconductors</i> , <b>2019</b> , 53, 1910-1913	0.7	4
87	Beryllium-Based Multilayer Mirrors for the Soft X-Ray and Extreme Ultraviolet Wavelength Ranges. <i>Journal of Surface Investigation</i> , <b>2020</b> , 14, 124-134	0.5	4
86	Phonon, plasmon and electronic properties of surfaces and interfaces of periodic W/Si and Si/W multilayers. <i>Physical Chemistry Chemical Physics</i> , <b>2021</b> , 23, 15076-15090	3.6	4
85	Current State of Development of a Microscope Operating at a Wavelength of 3.37 nm at the Institute of Physics of Microstructures of the Russian Academy of Sciences. <i>Journal of Surface Investigation</i> , <b>2018</b> , 12, 1253-1263	0.5	4
84	Vacuum Ultraviolet and Soft X-ray Broadband Monochromator for a Synchrotron Radiation Metrological Station. <i>Optoelectronics, Instrumentation and Data Processing</i> , <b>2019</b> , 55, 107-114	0.6	3
83	Stable Multilayer Reflective Coatings for $\lambda(\text{HeI}) = 58.4 \text{ nm}$ for the KORTES Solar Telescope. <i>Technical Physics Letters</i> , <b>2019</b> , 45, 85-88	0.7	3
82	Miniature Ion Source KLAN-10M with a Plasma Neutralizer. <i>Journal of Surface Investigation</i> , <b>2019</b> , 13, 182-187	0.5	3
81	X-ray scattering by the fused silica surface etched by low-energy Ar ions. <i>Journal of X-Ray Science and Technology</i> , <b>2019</b> , 27, 857-870	2.1	3
80	High performance multilayer La/B4C mirrors with carbon barrier layers. <i>Bulletin of the Russian Academy of Sciences: Physics</i> , <b>2014</b> , 78, 61-63	0.4	3
79	Influence of the chemical structure of (co)polymer resists on their sensitivity to radiation. <i>Bulletin of the Russian Academy of Sciences: Physics</i> , <b>2012</b> , 76, 159-162	0.4	3
78	Multilayer X-ray mirrors for the (4.4B)-nm carbon-window spectral region. <i>Crystallography Reports</i> , <b>2013</b> , 58, 505-508	0.6	3
77	Surface shape measurement of mirrors in the form of rotation figures by using point diffraction interferometer. <i>Journal of Modern Optics</i> , <b>2017</b> , 64, 413-421	1.1	3
76	Principles of certification of aspherical mirrors for an EUV lithography lens at a wavelength of 13.5 nm. <i>Journal of Surface Investigation</i> , <b>2015</b> , 9, 735-740	0.5	3
75	Effect of polymer matrix and photoacid generator on the lithographic properties of chemically amplified photoresist. <i>Russian Microelectronics</i> , <b>2014</b> , 43, 392-400	0.5	3
74	Reflective mask for projection lithography operating at a wavelength of 13.5 nm. <i>Journal of Surface Investigation</i> , <b>2012</b> , 6, 568-573	0.5	3
73	System for illumination of an EUV-nanolithograph mask. <i>Journal of Surface Investigation</i> , <b>2011</b> , 5, 517-518	0.5	3
72	A technological complex for manufacturing of precise imaging optics. <i>Bulletin of the Russian Academy of Sciences: Physics</i> , <b>2011</b> , 75, 53-56	0.4	3

71	New focusing multilayer structures for X-ray and VUV plasma spectroscopy. <i>Technical Physics</i> , <b>2010</b> , 55, 1018-1023	0.5	3
70	X-ray and vacuum-ultraviolet plasma spectroscopy with the use of new focusing multilayer structures. <i>JETP Letters</i> , <b>2008</b> , 87, 27-29	1.2	3
69	Development of Technological Principles for Creating a System of Microfocus X-Ray Tubes Based on Silicon Field Emission Nanocathodes. <i>Technical Physics</i> , <b>2019</b> , 64, 1742-1748	0.5	3
68	Microstructural Transformation of Nanoscale Be Layers in the Mo/Be and Be/Mo Periodic Multilayer Mirrors Investigated by Raman Spectroscopy. <i>Journal of Physical Chemistry C</i> , <b>2021</b> , 125, 2729-2738	3.8	3
67	Electron Energy Conversion to EUV Radiation in the K $\alpha$ Line of Be in the "Shooting Through" Geometry. <i>Journal of Experimental and Theoretical Physics</i> , <b>2018</b> , 127, 985-993	1	3
66	Aperiodic Mirrors Based on Multilayer Beryllium Systems. <i>Journal of Surface Investigation</i> , <b>2019</b> , 13, 267-271	0.5	2
65	High-resolution laboratory reflectometer for the study of x-ray optical elements in the soft and extreme ultraviolet wavelength ranges. <i>Review of Scientific Instruments</i> , <b>2020</b> , 91, 063103	1.7	2
64	Observation of Laser-Induced Spark in the Density Jump in a Gas-Jet Target. <i>Technical Physics Letters</i> , <b>2019</b> , 45, 970-972	0.7	2
63	Using Ion-beam etching to smooth fused silica surfaces. <i>Bulletin of the Russian Academy of Sciences: Physics</i> , <b>2014</b> , 78, 57-60	0.4	2
62	Thermal stability of a freestanding EUV filter under long-term vacuum annealing at 700-1000°C. <i>Journal of Surface Investigation</i> , <b>2012</b> , 6, 482-486	0.5	2
61	A laser plasma source of EUV radiation for projection nanolithography. <i>Bulletin of the Russian Academy of Sciences: Physics</i> , <b>2013</b> , 77, 6-9	0.4	2
60	SIMS depth profiling of Pd/B4C, Ni/C, and Cr/Sc multilayer metal structures using registration of cluster secondary ions: The problem of depth resolution enhancement. <i>Bulletin of the Russian Academy of Sciences: Physics</i> , <b>2011</b> , 75, 100-104	0.4	2
59	Details of how to mount high-precision optics. <i>Journal of Surface Investigation</i> , <b>2010</b> , 4, 359-365	0.5	2
58	Multilayer Cr/Sc Mirrors with Improved Reflection for the "Water Transparency Window" Range. <i>Technical Physics</i> , <b>2020</b> , 65, 1809-1813	0.5	2
57	Obtaining of Smooth High-Precision Surfaces by the Mechanical Lapping Method. <i>Technical Physics</i> , <b>2020</b> , 65, 1873-1879	0.5	2
56	Application of point diffraction interferometry for measuring angular displacement to a sensitivity of 0.01 arcsec. <i>Applied Optics</i> , <b>2015</b> , 54, 9315-9	0.2	2
55	Ultrasmooth beryllium substrates for solar astronomy in extreme ultraviolet wavelengths. <i>Applied Optics</i> , <b>2019</b> , 58, 3652-3658	1.7	2
54	Optical constants of sputtered beryllium thin films determined from photoabsorption measurements in the spectral range 20.4-250 eV. <i>Journal of Synchrotron Radiation</i> , <b>2020</b> , 27, 75-82	2.4	2

53	Faraday Isolator With Composite Magneto-Optical TGG-Sapphire Elements. <i>IEEE Journal of Quantum Electronics</i> , <b>2021</b> , 57, 1-8	2	2
52	Problems and prospects of maskless (B)EUV lithography <b>2016</b> ,		2
51	Influence of Thermal Annealing on the Properties of Multilayer Mo/Be Mirrors. <i>Technical Physics</i> , <b>2019</b> , 64, 1692-1697	0.5	2
50	Influence of Beryllium Barrier Layers on the Properties of Mo/Si Multilayer Mirrors. <i>Technical Physics</i> , <b>2019</b> , 64, 1688-1691	0.5	2
49	Simulation of Local Error Correction of the Surface Shape by a Low-Dimensional Ion Beam. <i>Technical Physics</i> , <b>2019</b> , 64, 1560-1565	0.5	2
48	Size-dependent plasmon effects in periodic W-Si- based mirrors, investigated by X-ray photoelectron spectroscopy. <i>Applied Surface Science</i> , <b>2021</b> , 566, 150616	6.7	2
47	Diffraction-limited short-wavelength optics: Analysis, fabrication, and application. <i>Journal of Surface Investigation</i> , <b>2012</b> , 6, 464-472	0.5	1
46	Nanostructure formation on an EUV lithographer stand: First results. <i>Bulletin of the Russian Academy of Sciences: Physics</i> , <b>2013</b> , 77, 1-5	0.4	1
45	The effect of bombardment with neutralized neon ions on the roughness of a fused silica and beryllium surface. <i>Journal of Surface Investigation</i> , <b>2017</b> , 11, 485-489	0.5	1
44	Comparative characteristics of optical methods for measuring the surface shape at the institute for physics of microstructures, Russian Academy of Sciences. <i>Journal of Surface Investigation</i> , <b>2015</b> , 9, 741-744	0.5	1
43	Multilayer x-ray mirrors based on W/B 4 C with ultrashort ( $d = 0.7 \pm 0.5$ nm) periods. <i>Journal of Surface Investigation</i> , <b>2007</b> , 1, 7-12	0.5	1
42	Effect of pinhole roughness on light diffraction. <i>Journal of Surface Investigation</i> , <b>2008</b> , 2, 511-513	0.5	1
41	Broadband Mirrors for Spectroheliographs at the KORTES Sun Study Facility. <i>Technical Physics</i> , <b>2020</b> , 65, 1792-1799	0.5	1
40	Application of Novel Multilayer Normal-Incidence Mirrors for EUV Solar Spectroscopy. <i>Technical Physics</i> , <b>2020</b> , 65, 1736-1739	0.5	1
39	The Smoothing Effect of Si Layers in Multilayer Be/Al Mirrors for the 17- to 31-nm Range. <i>Technical Physics</i> , <b>2020</b> , 65, 1786-1791	0.5	1
38	Mirrors with a Subnanometer Surface Shape Accuracy <b>2013</b> , 595-616		1
37	Prospects for the Use of X-Ray Tubes with a Field-Emission Cathode and a Through-Type Anode in the Range of Soft X-Ray Radiation. <i>Technical Physics</i> , <b>2020</b> , 65, 1726-1735	0.5	1
36	Measurement Error of Interferometers with Diffraction Reference Wave. <i>Technical Physics</i> , <b>2019</b> , 64, 1698-1703	0.5	1



35	Multilayer Ag/Y Mirrors for the Spectral Range of 911 nm. <i>Technical Physics</i> , <b>2019</b> , 64, 1684-1687	0.5	1
34	Beryllium as a Material for Thermally Stable X-Ray Mirrors. <i>Technical Physics</i> , <b>2019</b> , 64, 1596-1601	0.5	1
33	Fabrication and Study of a Concave Crystal Mirror for the KORTES Project. <i>Technical Physics</i> , <b>2019</b> , 64, 1680-1683	0.5	1
32	Modular Device for the Formation and Study of Cluster Beams of Inert and Molecular Gases. <i>Journal of Surface Investigation</i> , <b>2019</b> , 13, 862-869	0.5	1
31	Optimization of Composition, Synthesis, and Study of Broadband Multilayer Mirrors for the EUV Spectral Range. <i>Technical Physics</i> , <b>2019</b> , 64, 1673-1679	0.5	1
30	Inhibition of chemical interaction of molybdenum and silicon in a Mo/Si multilayer structure by the formation of intermediate compounds. <i>Physical Chemistry Chemical Physics</i> , <b>2021</b> , 23, 1363-1370	3.6	1
29	Emission Spectra of Light Inert Gases Ne and Ar in the 320 nm Range under Pulsed Laser Excitation Using Various Gas Jets as Targets. <i>Optics and Spectroscopy (English Translation of Optika i Spektroskopiya)</i> , <b>2021</b> , 129, 185-190	0.7	1
28	Phase analysis of tungsten and phonon behavior of beryllium layers in W/Be periodic multilayers. <i>Physical Chemistry Chemical Physics</i> , <b>2021</b> , 23, 23303-23312	3.6	1
27	Optical, Mechanical, and Thermal Properties of Free-Standing MoSi <sub>2</sub> N <sub>x</sub> and ZrSi <sub>2</sub> N <sub>y</sub> Nanocomposite Films. <i>Technical Physics</i> , <b>2019</b> , 64, 1590-1595	0.5	0
26	Microstructure and phonon behavior in W/Si periodic multilayer structures. <i>Journal Physics D: Applied Physics</i> , <b>2022</b> , 55, 175302	3	0
25	The Microstructure of Transition Boundaries in Multilayer Mo/Be Systems. <i>Technical Physics</i> , <b>2020</b> , 65, 1800-1808	0.5	0
24	Ion-Beam Methods for High-Precision Processing of Optical Surfaces. <i>Technical Physics</i> , <b>2020</b> , 65, 1837-1845	0.5	0
23	Intrinsic roughness and interfaces of Cr/Be multilayers. <i>Journal of Applied Crystallography</i> , <b>2021</b> , 54, 1743-1756	3.8	0
22	Investigation of microstructure and reflectivity of thermally annealed Mo/Be and W/Be multilayer mirrors. <i>Surfaces and Interfaces</i> , <b>2022</b> , 28, 101656	4.1	0
21	Influence of ion-beam etching by Ar ions with an energy of 200-1000 eV on the roughness and sputtering yield of a single-crystal silicon surface. <i>Applied Optics</i> , <b>2022</b> , 61, 2825-2833	1.7	0
20	Microstructure and Density of Mo Films in Multilayer Mo/Si Mirrors. <i>Journal of Surface Investigation</i> , <b>2019</b> , 13, 8-13	0.5	
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